

Corres. and Mail  
**BOX AF**

*ILW AF 1765*

Response Under 37 C.F.R. § 1.116  
Expedited Procedure  
Examining Group 1765  
PATENT



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:	)	
Wen-Ben CHOU et al.	)	Docket No. LAM2P295
Application No. 09/998,858	)	Examiner: Chen, Kin Chan
Filed: October 31, 2001	)	Group Art Unit: 1765
For: METHOD AND APPARATUS	)	Date: November 16, 2004
FOR NITRIDE SPACER ETCH	)	
PROCESS IMPLEMENTING -	)	
IN SITU INTERFEROMETRY	)	
ENDPOINT DETECTION AND	)	
NON-INTERFEROMETRY	)	
ENDPOINT MONITORING	)	

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450 on November 16, 2004.

Signed: 

Courtney F. Yadegar

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

*Do not enter.*

*kcc 11/29/04*

**AMENDMENT**

Dear Sir:

This is in response to the Final Office Action mailed on August 16, 2004. Please enter the following Amendments and remarks in the above-identified patent application:

Amendments to the claims are provided in the Listing of Claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 8 of this paper.